ABSTRACT

A method of producing a gas discharge panel capable of an efficient exhausting in the exhaust process. In a vacuum pumping process, with an open/close valve (53f) opened to a suitable degree while heating (baking) a heating furnace (51) to a temperature (exhaust baking temperature) lower than the softening temperature of a sealant layer, a turbo-molecular pump (53b) and a rotary pump (53c) are actuated to evacuate an envelope (40) until a vacuum is created, whereupon a discharge gas is introduced from a gas introducing system (52) into the envelope (40) until a predetermined pressure (for example, 0.05MPa) is produced therein. Thereafter, the discharge gas introduction from the gas introducing system (52) is stopped, and the discharge gas in the envelope is sucked out through a suction exhaust system (53), thereby re-establishing a vacuum state in the envelope (40).